

**RECEIVED  
CENTRAL FAX CENTER**

Application No.: 10/603,924

JUN 15 2005

Docket No.: JCLA7109

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re Application of : )  
Shao-Chung Hu et al. )  
Serial No. : 10/603,924 )  
Filed : 06/24/2003 )  
For : Post-CMP Removal Of Surface )  
Contaminants From Silicon Wafer )

) Examiner : NGUYEN, THANH T  
) Art Unit : 2813  
) Docket No. : JCLA7109

---

No fee is believed to be due. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-0710 (Order No. JCLA7109).

**AMENDMENT AND RESPONSE TO OFFICE ACTION**

**MAIL STOP Amendment**  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir,

The Office Action mailed on March 16, 2005 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.